



**PATENT APPLICATION
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Docket No: Q60716

Hiromoto OHNO, et al.

Appln. No. 10/088,306

Group Art Unit: 3749

Confirmation No.: 2926

Examiner: Not Yet Assigned

Filed: March 18, 2002

For: **CLEANING GAS FOR SEMICONDUCTOR PRODUCTION EQUIPMENT**

**SUBMISSION OF CORRECTED VERSION OF PCT NOTIFICATION
CONCERNING PRIORITY DATA**

Commissioner for Patents
Washington, D.C. 20231

Sir:

Applicants submit herewith Form PCT/IB/304 for PCT Application No. PCT/JP01/06164 (assigned Application No. 10/088,306) and the Corrected Version of the front page of the PCT application. The corrected PCT Notification corrects the filing date of JP 2000-397269 from which Applicant's claim foreign priority under 35 U.S.C. § 119. The correct priority date is reflected in Applicants' Declaration and Power of Attorney filed March 18, 2002.

Respectfully submitted,

Abraham J. Rosner
Registration No. 33,276

SUGHRUE MION, PLLC
2100 Pennsylvania Avenue, N.W.
Washington, D.C. 20037-3213
Telephone: (202) 293-7060
Facsimile: (202) 293-7860

Date: June 25, 2002

RECEIVED

JUN 27 2002

TECHNOLOGY CENTER R3700